



※Capable of docking with EFEM

可对全面板尺寸进行检测
Capable of Testing Full Panel Size
(515x510mm)

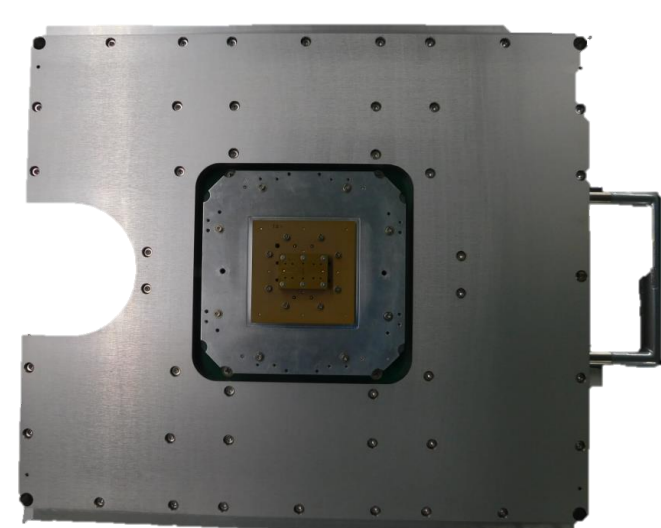
可对应上侧最大检测点数24Kch
Max testing points are 24Kch
(Up to 24Kch Test Point)

SEMI规格标准
Following SEMI Standard

采用Glass Carrier的FOPLP/RDL电气检测解决方案 For Full-Panel size PLP with Glass Carrier, High Speed, High Accuracy Probing Electrical Test System

综合对位精度 $\pm 3.5\mu\text{m}$
Comprehensive alignment accuracy $\pm 3.5\mu\text{m}$

上侧最大24K对应治具/Tester
Max 24K for top fixtures/tester



■ Fixture

可对应上侧最大检测点数24Kch
* 对应机型: R59XX型
Fixture with up to 24Kch points
* Limited to models with R59XX tester
探针的最小直径: $15\mu\text{m}$
*根据焊盘布局, 我们灵活选用多样化探针类型, 提供最优化的检测治具设计方案。
Minimum diameter of probe : $15\mu\text{m}$
*Propose the most suitable Fixture design from a variety of probes according to the pad layout.

SEMI规格标准
Following SEMI Standard

Safety : SEMI S2,S8
Communication : E84
SECS/GEM, Gem300 *Option
Automation
: PGV/AGV operation *Option

可检测两种类型的RDL
Available for two types of RDL test

■ **Insulated type (R-7XX Tester)**
Continuity inspection solution for AC measurement.



■ **Conductive type (R-59XX Tester)**
Insulation inspection solution for DC inspection.



Key Specification

检测单元 Inspection section	Step & Repeat mechanism
Max检测点数 Maximum Test point	Top: 24576ch (4Kch*6QD-Block)
工件尺寸 Work Size	(W) 515mm × (D) 510mm
工件厚度 Thickness	0.4~3.5mm
KOZ (MIN)	Left & Right side = 8mm
综合对位精度 Alignment accuracy	$\pm 3.5\mu\text{m}$
工作台面 Work Holder	Lifting-type table (Jig fixed to above)
设备尺寸 Equipment size	(W) 1,931* × (D) 2,430* × (H) 2,093mm (Without L/UL)

※该设备正在开发中, 可能与实际规格有所不同。
※This system is under development. so the actual machine specification could be changed.